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Date Sent: September 19, 2007

No of Pages: 15
(including cover page)

COMMENTS

Serial No. 10/686,898

Filed: October 15, 2003

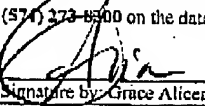
Patent No. 6,933,011

Issued: August 23, 2005

Atty docket no. 67538-5174 US

The following documents are being faxed herewith:

- * Transmittal of Power of Attorney By Assignee. (1) page;
- * Revocation and Power of Attorney with Schedule A (12) pages;
- * Power of Attorney with Statement Under 37 C.F.R. § 3.73(b) (1) page.

Certificate Of Facsimile Transmission under 37 C.F.R. 61.8: I hereby certify that this correspondence is being transmitted by facsimile to the United States Patent and Trademark Office, to fax number (574) 273-8300 on the date shown below.  Signature by: Grace Alicen 9-19-07 Dated:		RECEIVED IN THE UNITED STATES PATENT AND TRADEMARK OFFICE CENTRAL FAX CENTER	
Application of:	Yoshihide Senzaki	Confirmation No.:	7540 SEP 19 2007
Serial No.	10/686,898	Art Unit:	1762
Patent No.	6,933,011	Examiner:	Chen, Bret P.
Filed:	October 15, 2003	Attorney	67538-5174 US
Issued:	August 23, 2005	Docket No:	
For:	TWO-STEP ATOMIC LAYER DEPOSITION OF COPPER LAYERS		

TRANSMITTAL OF POWER OF ATTORNEY BY ASSIGNEE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:


Applicant's attorney encloses herewith a Revocation and Power of Attorney by Assignee with Statement Under 37 CFR 3.73(b) for the above identified application.

Please refer to attorney docket number 67538-5174-US. Future correspondence should be forwarded to customer no. 24341.

The Commissioner is authorized to charge any fees associated with this communication to Morgan, Lewis & Bockius LLP deposit account no. 50-0310 (order no. 67538-5174-US).

Date: Sept. 19, 2007

Respectfully submitted,


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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of: See Attached Schedule A

Serial No.: See Attached Schedule A

Filed: See Attached Schedule A

For: See Attached Schedule A

Attorney Docket No: See Attached
Schedule AREVOCATION AND POWER OF ATTORNEYCommissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

S I R:

Aviza Technology, Inc., owner of the entire right, title and interest in, to and under the inventions listed in the attached Schedule A, hereby revokes all previous powers of attorney and appoints the registered attorneys at Morgan, Lewis & Bockius LLP associated with Customer No. 24341 as its attorneys to prosecute these matters, and to transact all business in the Patent and Trademark Office connected therewith, said appointment to be to the exclusion of the inventors and their attorney(s) in accordance with the provisions of 37 C.F.R. 3.71, provided that, if any one of these attorneys ceases being affiliated with the law firm of Morgan, Lewis & Bockius LLP as partner, counsel, or employee, then the appointment of that attorney and all powers derived therefrom shall terminate on the date such attorney ceases being so affiliated.

Please direct all future correspondence to the address associated with Customer No. 24341, Morgan, Lewis & Bockius LLP and direct all telephone calls to Morgan, Lewis & Bockius LLP at (650) 843-4000.

Date: 08/03/2007

Assignee: Aviza Technology, Inc.

Signature: Typed Name: Nitin ShahPosition/Title: Vice PresidentAddress: 440 Kings Village Road
Scotts Valley, California 95066

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SEP 19 2007

SCHEDULE A

Serial No./ Patent No.	Filing Date/ Issued Date	Title	First Named Inventor	Docket No.
07/068,727 4,845,054	06/29/1987 07/04/1989	LOW TEMPERATURE CHEMICAL VAPOR DEPOSITION OF SILICON DIOXIDE FILMS	James C. Mitchener	67538-3001-US01
07/750,122 5,088,773	08/17/1990 02/19/1992	ELECTRICALLY INSULATING PIPE COUPLING APPARATUS	Nicholas M. Gralenski	67538-5007-US
07/542,243 5,136,975	06/21/1990 08/11/1992	INJECTOR AND METHOD FOR DELIVERING GASEOUS CHEMICALS TO A SURFACE	Lawrence D. Bartholomew	67538-5008-US
07/513,807 5,113,789	04/24/1990 05/19/1992	SELF CLEANING FLOW CONTROL ORIFICE	George D. Kamian	67538-5009-US
11/239,880	09/30/2005	METHOD AND APPARATUS FOR LOW TEMPERATURE DIELECTRIC DEPOSITION USING MONOMOLECULAR PRECURSORS	Cole Porter	67538-5010-US
11/496,993	07/31/2006	GAS MANIFOLD VALVE CLUSTER	Craig Bercaw	67538-5013-US
11/496,787	07/31/2006	DEPOSITION APPARATUS FOR SEMICONDUCTOR PROCESSING	Craig Bercaw	67538-5014-US
11/400,366	04/07/2006	MULTILAYER, MULTICOMPONENT HIGH-K FILMS AND METHODS FOR DEPOSITING THE SAME	Lawrence D. Bartholomew	67538-5015-US

Serial No./ Patent No.	Filing Date/ Issued Date	Title	First Named Inventor	Docket No.
11/482,782	07/07/2006	METHOD FOR DEPOSITING SILICON- CONTAINING FILMS	Yoshikazu Okuyama	67538-5016-US
11/356,707	01/07/2006	APPARATUS AND METHOD FOR THE DEPOSITION OF RUTHENIUM CONTAINING FILMS	Helmuth Treichel	67538-5019-US
11/359,264	02/21/2006	METHODS AND APPARATUS FOR PROCESSING WAFERS	Nicholas John Appleyard	67538-5023-US
60/831,538	07/17/2006	SUBSTRATE HANDLING APPARATUS	Gordon Robert Green	67538-5024 PR
60/831,718	07/17/2006	MICROFLUIDIC DEVICES	Gordon Robert Green	67538-5025 PR
60/832,474	07/20/2006	ION DEPOSITION APPARATUS	Gary Proudfoot	67538-5026 PR
60/832,378	07/20/2006	PLASMA SOURCES	Gary Proudfoot	67538-5027 PR
60/832,428	07/20/2006	ION SOURCES	Gary Proudfoot	67538-5028 PR
07/601,270 5,078,922	10/22/1990 01/07/1992	LIQUID SOURCE BUBBLER	Craig C. Collins	67538-5030-US

Serial No./ Patent No.	Filing Date/ Issued Date	Title	First Named Inventor	Docket No.
07/601,408 5,029,471	10/23/1990 07/09/1991	LIQUID LEVEL SENSOR ASSEMBLY	Gary B. Goodrich	67538-5032-US
07/971,490 5,377,300	11/04/1992 12/27/1994	HEATER FOR PROCESSING GASES	Craig C. Collins	67538-5035-US
08/621,772 5,683,516	03/22/1996 11/04/1997	SINGLE BODY INJECTOR AND METHOD FOR DELIVERING GASES TO A SURFACE	Jay B. DeDontney	67538-5043 US01
08/869,085 5,935,647	06/04/1997 08/10/1999	METHOD OF MANUFACTURING AN INJECTOR FOR CHEMICAL VAPOR DEPOSITION PROCESSING	Jay B. DeDontney	67538-5043 US02
08/892,469 6,022,414	07/14/1997 02/08/2000	SINGLE BODY INJECTOR AND METHOD FOR DELIVERING GASES TO A SURFACE	Adam Q. Miller	67538-5043 US03
09/113,823 6,200,389	07/10/1998 03/13/2001	SINGLE BODY INJECTOR AND DEPOSITION CHAMBER	Adam Q. Miller	67538-5043 US04
09/757,542 6,521,048	01/09/2001 02/18/2003	SINGLE BODY INJECTOR AND DEPOSITION CHAMBER	Adam Q. Miller	67538-5043 US05
08/704,227 5,786,278	08/27/1996 07/28/1998	METHOD OF STRESS- RELIEVING SILICON OXIDE FILMS	H. Wallace Fry	67538-5045-US
08/976,928 5,944,900	11/24/1997 08/31/1999	PROTECTIVE GAS SHIELD FOR CHEMICAL VAPOR DEPOSITION APPARATUS	Don Van Tran	67538-5046 US01

Serial No./ Patent No.	Filing Date/ Issued Date	Title	First Named Inventor	Docket No.
08/801,997 5,855,957	02/18/1997 01/05/1999	OPTIMIZING OF SiO ₂ FILM CONFORMALITY IN ATMOSPHERIC PRESSURE CHEMICAL VAPOR DEPOSITION	Zheng Yuan	67538-5050-US
09/019,349 5,976,258	02/05/1998 11/02/1999	HIGH TEMPERATURE SUBSTRATE TRANSFER MODULE	Timothy Norpell Kleiner	67538-5054-US
08/796,300 5,921,560	02/07/1997 07/13/1999	DIRECT DRIVE ROTATIONAL MOTOR WITH AXIAL VACUUM	Rick S. Moshtagh et al.	67538-5062-US
08/838,882 5,938,851	04/14/1997 08/17/1999	EXHAUST VENT ASSEMBLY FOR CHEMICAL VAPOR DEPOSITION SYSTEMS	Rick S. Moshtagh	67538-5064-US
09/018,021 6,026,589	02/02/1998 02/22/2000	WAFER CARRIER AND SEMICONDUCTOR APPARATUS FOR PROCESSING A SEMICONDUCTOR SUBSTRATE	Jack Chihchieh Yao	67538-5072-US
09/008,024 5,849,088	01/16/1998 12/15/1998	FREE FLOATING SHIELD	Jay B. DeDontney	67538-5074-US
09/185,180 6,056,824	11/03/1998 05/02/2000	FREE FLOATING SHIELD AND SEMICONDUCTOR PROCESSING SYSTEM	Lawrence D. Bartholomew	67538-5074 US01
09/492,420 6,352,592	01/27/2000 03/05/2002	FREE FLOATING SHIELD AND SEMICONDUCTOR PROCESSING SYSTEM	Lawrence D. Bartholomew	67538-5074 US02
10/637,913 7,153,580	08/08/2003 12/26/2006	LOW K DIELECTRIC INORGANIC/ORGANIC HYBRID FILMS AND METHOD OF MAKING	Peter Rose	67538-5075 US02

Serial No./ Patent No.	Filing Date/ Issued Date	Title	First Named Inventor	Docket No.
11/606,425	11/29/2006	LOW K DIELECTRIC INORGANIC/ORGANIC HYBRID FILMS AND METHOD OF MAKING	Peter Rose	67538-5075 US03
09/067,704 6,068,884	04/28/1998 05/30/2000	METHOD OF MAKING LOW k DIELECTRIC INORGANIC/ORGANIC HYBRID FILMS	Peter Rose	67538-5075-US
09/361,667 6,660,391	07/27/1999 12/09/2003	LOW K DIELECTRIC INORGANIC/ORGANIC HYBRID FILMS AND METHOD OF MAKING FREQUENCY APPLICATIONS	Peter Rose	67538-5075 US01
09/493,492 6,143,080	01/28/2000 11/07/2000	WAFER PROCESSING REACTOR HAVING A GAS FLOW CONTROL SYSTEM AND METHOD	Lawrence D. Bartholomew	67538-5078-US
09/905,349	07/13/2001	GAS DELIVERY METERING TUBE	Jay Brian DeDontmey	67538-5079 US01
07/386,903 4,993,358	07/28/1989 02/19/1991	CHEMICAL VAPOR DEPOSITION REACTOR AND METHOD OF OPERATION	Imad Mahawili	67538-5081-US
07/409,125 5,059,770	09/19/1989 10/22/1991	MULTI-ZONE PLANAR HEATER ASSEMBLY AND METHOD OF OPERATION	Imad Mahawili	67538-5082-US
07/668,858 5,122,391	03/13/1991 06/16/1992	METHOD FOR PRODUCING HIGHLY CONDUCTIVE AND TRANSPARENT FILMS OF TIN AND FLUORINE DOPED INDIUM OXIDE BY APCVD	Bruce E. Mayer	67538-5084-US
09/574,826 6,576,060	05/19/2000 06/10/2003	PROTECTIVE GAS SHIELD APPARATUS	D. Neil Stoddard	67538-5085-US

Serial No./ Patent No.	Filing Date/ Issued Date	Title	First Named Inventor	Docket No.
09/541,395 6,387,764	03/31/2000 05/14/2002	TRENCH ISOLATION PROCESS TO DEPOSIT A TRENCH FILL OXIDE PRIOR TO SIDEWALL LINER OXIDATION GROWTH	Todd O. Curtis	67538-5086-US
09/996,869 6,846,149	11/27/2001 01/25/2005	SEMICONDUCTOR WAFER PROCESSING SYSTEM WITH VERTICALLY-STACKED PROCESS CHAMBERS AND SINGLE-AXIS DUAL- WAFER TRANSFER SYSTEM	Richard N. Savage	67538-5087 US02
09/480,730 6,206,973	01/06/2000 03/27/2001	CHEMICAL VAPOR DEPOSITION SYSTEM AND METHOD	Robert J. Bailey	67538-5089-US
09/542,612 6,465,044	04/04/2000 10/15/2002	CHEMICAL VAPOR DEPOSITION OF SILICON OXIDE FILMS USING ALKYLSILOXANE OLIGOMERS WITH OZONE	Sanjeev Jain	67538-5091-US
08/563,875 5,618,351	11/28/1995 04/08/1997	THERMAL PROCESSING APPARATUS AND PROCESS	Terry A. Koble	67538-5099 US01
06/880,460 4,721,424	06/30/1988 01/26/1988	SEMICONDUCTOR WAFER BOAT LOADER RELEASEABLE MOUNTING	Robert E. Aldridge	67538-5100 US01
08/827,542 6,005,225	03/28/1997 12/21/1999	THERMAL PROCESSING APPARATUS	Jeffrey M. Kowalski	67538-5102-US
09/022,056 6,101,844	02/10/1998 08/15/2000	DOUBLE WALL REACTION CHAMBER GLASSWARE	Jack D. Fowler	67538-5103-US
09/373,894 6,300,600	08/12/1999 10/09/2001	HOT WALL RAPID THERMAL PROCESSOR	Christopher Ratliff	67538-5104-US

Serial No./ Patent No.	Filing Date/ Issued Date	Title	First Named Inventor	Docket No.
09/638,113 6,462,310	08/11/2000 10/08/2002	HOT WALL RAPID THERMAL PROCESSOR	Christopher Ratliff	67538-5104-US01
09/934,952 6,492,621	08/21/2001 12/10/2002	HOT WALL RAPID THERMAL PROCESSOR	Christopher Ratliff	67538-5104-US02
10/262,215 6,844,528	09/30/2002 01/18/2005	HOT WALL RAPID THERMAL PROCESSOR	Christopher Ratliff	67538-5104-US03
10/261,963 6,900,413	09/30/2002 05/31/2005	HOT WALL RAPID THERMAL PROCESSOR	Christopher Ratliff	67538-5104-US04
06/899,923 4,720,395	08/25/1986 01/19/1988	LOW TEMPERATURE SILICON NITRIDE CVD PROCESS	Derrick W. Foster	67538-5106-US
07/181,787 4,886,954	04/15/1988 12/12/1989	HOT WALL DIFFUSION FURNACE AND METHOD FOR OPERATING THE FURNACE	Chorng-Tao Yu	67538-5108-US
06/864,676 4,711,989	05/19/1986 12/08/1987	DIFFUSION FURNACE MULTIZONE TEMPERATURE CONTROL	Chorng-Tao Yu	67538-5111-US
07/048,868 4,721,427	05/12/1987 01/26/1998	WAFER TRANSFER STAND	John D. Sanders	67538-5113-US
09/628,471 6,476,921	07/31/2000 11/05/2002	IN-SITU METHOD AND APPARATUS FOR END POINT DETECTION IN CHEMICAL MECHANICAL POLISHING	Nannaji Saka	67538-5117-US

Serial No./ Patent No.	Filing Date/ Issued Date	Title	First Named Inventor	Docket No.
09/628,563 6,984,168	07/31/2000 01/10/2006	APPARATUS AND METHOD FOR CHEMICAL MECHANICAL POLISHING OF SUBSTRATES	Jason Melvin	67538-5118-US
10/029,158 7,029,381	12/21/2001 04/18/2006	APPARATUS AND METHOD FOR CHEMICAL MECHANICAL POLISHING OF SUBSTRATES	Jason Melvin	67538-5118 US01
09/628,962 6,458,013	07/31/2000 10/01/2002	METHOD OF CHEMICAL MECHANICAL POLISHING	Nannaji Saka	67538-5119-US
10/057,477 6,667,239	01/23/2002 12/23/2003	CHEMICAL MECHANICAL POLISHING OF COPPER- OXIDE DAMASCENE STRUCTURES	Nannaji Saka	67538-5120-US
06/864,077 4,770,590	05/16/1986 09/13/1988	METHOD AND APPARATUS FOR TRANSFERRING WAFERS BETWEEN CASSETTES AND A BOAT	Jean B. Hugues	67538-5121-US
10/095,974 6,864,466	03/08/2002 03/08/2005	SYSTEM AND METHOD TO CONTROL RADIAL DELTA-TEMPERATURE	Cole Porter	67538-5122-US
10/068,127 6,901,317	02/06/2002 05/31/2005	INERTIAL TEMPERATURE CONTROL SYSTEM AND METHOD	Alan Starner	67538-5123-US
10/056,625 6,713,846	01/25/2002 03/30/2004	MULTILAYER HIGH K DIELECTRIC FILMS	Yoshihide Senzaki	67538-5127-US
10/766,618	01/27/2004	MULTILAYER HIGH K DIELECTRIC FILMS AND METHOD OF MAKING THE SAME	Yoshihide Senzaki	67538-5127 US02

Serial No./ Patent No.	Filing Date/ Issued Date	Title	First Named Inventor	Docket No.
10/306,205 6,874,770	11/27/2002 04/05/2005	HIGH FLOW RATE BUBBLER SYSTEM AND METHOD	Amir Torkaman	67538-5128-US 4
10/194,639 6,890,386	07/12/2002 05/10/2005	MODULAR INJECTOR AND EXHAUST ASSEMBLY	Jay Brian DeDontney	67538-5131-US
11/114,746	04/25/2005	MODULAR INJECTOR AND EXHAUST ASSEMBLY	Jay Brian DeDontney	67538-5131 US01
10/226/439	08/23/2002	PROTECTIVE SHIELD AND SYSTEM FOR GAS DISTRIBUTION	Colby Mattson	67538-5135-US
10/226/773 6,761,770	08/23/2002 07/13/2004	ATMOSPHERIC PRESSURE WAFER PROCESSING REACTOR HAVING AN INTERNAL PRESSURE CONTROL SYSTEM AND METHOD	Lawrence D. Bartholomew	67538-5136-US
10/456,850 7,109,131	06/06/2003 09/19/2006	SYSTEM AND METHOD FOR HYDROGEN-RICH SELECTIVE OXIDATION	Robert B. Herring	67538-5145-US
10/519,331	04/18/2005	METHOD FOR ENERGY- ASSISTED ATOMIC LAYER DEPOSITION AND REMOVAL	Aubrey L. Helms Jr.	67538-5148 US01
10/854,869 6,921,437	05/26/2004 07/26/2005	GAS DISTRIBUTION SYSTEM	Jay Brian. DeDontney	67538-5158-US
11/142,087	05/31/2005	GAS DISTRIBUTION SYSTEM	Jay Brian. DeDontney	67538-5158 US01

Serial No./ Patent No.	Filing Date/ Issued Date	Title	First Named Inventor	Docket No.
11/205,431	08/16/2005	DIRECT LIQUID INJECTION SYSTEM AND METHOD FOR FORMING MULTI-COMPONENT DIELECTRIC FILMS	Yoshihide Senzaki	67538-5161-US
10/521/636	01/19/2005	IN-SITU FORMATION OF METAL INSULATOR METAL CAPACITORS CROSS REFERENCE TO RELATED APPLICATIONS	Yoshihide Senzaki	67538-5167-US
10/524,814	08/18/2003	ATOMIC LAYER DEPOSITION OF HIGH-K METAL OXIDES	Sang-In Lee	67538-5170-US
10/525,122	03/20/2006	ATOMIC LAYER DEPOSITION OF HIGH-K METAL SILICATES	Sang-In Lee	67538-5171-US
10/524,980	03/22/2006	LOW TEMPERATURE DEPOSITION OF SILICON OXIDES AND OXYNITRIDES	Yoshihide Senzaki	67538-5172-US
10/686,898	10/15/2003	TWO-STEP ATOMIC LAYER DEPOSITION OF COPPER LAYERS	Yoshihide Senazaki	67538-5174-US
10/521,619	01/14/2005	THERMAL PROCESSING SYSTEM AND CONFIGURABLE VERTICAL CHAMBER	Dale R. Du Bois	67538-5177-US
10/521,283	02/28/2005	VARIABLE HEATER ELEMENT FOR LOW TO HIGH TEMPERATURE RANGES	Qiu Taiqing	67538-5190-US
10/954,819	09/29/2004	ATOMIC LAYER DEPOSITION OF HAFNIUM-BASED HIGH-K DIELECTRIC	Sang-In Lee	67538-5195-US

SEP 19 2007

Serial No./ Patent No.	Filing Date/ Issued Date	Title	First Named Inventor	Docket No.
10/829,781	04/21/2004	SYSTEM AND METHOD FOR FORMING MULTI- COMPONENT DIELECTRIC FILMS	Yoshihide Senzaki et al.	67538-5198-US
10/869,779	06/15/2004	SYSTEM AND METHOD FOR FORMING MULTI- COMPONENT DIELECTRIC FILMS	Yoshihide Senzaki	67538-5198 US01
11/166,258	06/24/2005	SYSTEM AND METHOD FOR FORMING MULTI- COMPONENT DIELECTRIC FILMS	Yoshihide Senzaki	67538-5198 US02
11/165,876	06/24/2005	SYSTEM AND METHOD FOR FORMING MULTI- COMPONENT DIELECTRIC FILMS	Yoshihide Senzaki	67538-5198 US03
10/919,666	08/16/2004	NITRIDATION OF HIGH-K DIELECTRIC FILMS	Yoshihide Senzaki	67538-5210-US
11/179,078	07/11/2005	DEPOSITION OF RUTHENIUM AND/OR RUTHENIUM OXIDE FILMS	Yoshihide Senzaki	67538-5212-US

SEP 19 2007

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of:	Yoshihide Senzaki	Confirmation No.:	7540
Serial No.	10/686,898	Art Unit:	1762
Patent No.	6,933,011	Examiner:	Chen, Bret P.
Filed:	October 15, 2003	Attorney	67538-5174 US
Issued:	August 23, 2005	Docket No:	(previously A-71731, 463035-861)
For:	TWO-STEP ATOMIC LAYER DEPOSITION OF COPPER LAYERS		

STATEMENT UNDER 37 C.F.R. § 3.73(b)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Aviza Technology, Inc., a corporation, states that it is the assignee of the entire right, title and interest in the patent application/patent identified above by virtue of an assignment from the inventor(s) of the patent application/patent identified above.

A chain of title from the inventor(s), of the patent application/patent identified above, to the current assignee as shown below:

1. From: Yoshihide Senzaki

To: Aviza Technology, Inc.

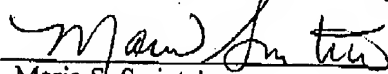
The document was recorded in the United States Patent and Trademark Office on May 26, 2004 at Reel 015396, Frame 0138;

2. From: Yoshihide Senzaki

To: Aviza Technology, Inc.

The document was recorded in the United States Patent and Trademark Office on December 31, 2004 at Reel 016129, Frame 0290;

The undersigned is authorized to act on behalf of the assignee.

Date: Sept. 19, 2007

Maria S. Swiatek

Customer No. 24341

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37,244
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